

In the Specification

Please replace the paragraph at page 1, lines 6-9 with the following::

A1

This patent document is related to and incorporates by reference in its entirety, co-owned U.S. patent application Ser. No. 09/113,484, entitled "System using a Polar Coordinate Stage and Continuous Image Rotation to Compensate for Stage Rotation," filed July 10, 1998, issued on November 20, 2001 as US 6,320,609 B1.

Please replace the paragraph at page 8, lines 7-15 with the following:

A2

In an exemplary embodiment, imaging system 330 includes an optical microscope that provides a field of view at wafer 350 which is about 1.3 mm x 1 mm. An aperture in mirror 334 passes light from a small spot (about 15 microns in diameter) at the center of the field of view of objective 140 to spectrometer 338 which collects data on the reflectance. This data can be used for determining the film thickness. U.S. patent App. entitled "Compact Optical Reflectometer System," of R. Yarussi and Blaine R. Spady, Ser. No. 09/347,362, ~~Attorney~~ docket no. 7556-0001, issued on January 30, 2001 as US 6,181,427 B1, describes some suitable measuring and imaging systems and is hereby incorporated by reference in its entirety.

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